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1. An Ink-jet head using diaphragm microactuator  
Hirata, S.; Ishii, Y.; Matoba, H.; Inui, T.;  
Micro Electro Mechanical Systems, 1996, MEMS '96, Proceedings. 'An Investigation of Micro Structures, Sensors, A  
Machines and Systems'. IEEE, The Ninth Annual International Workshop on  
11-15 Feb. 1996 Page(s):418 - 423  
[AbstractPlus](#) | Full Text: [PDF\(672 KB\)](#) IEEE CNF
2. Silicon-on-Insulator integrated optical biosensors for environmental monitoring  
Newman, J.D.; Turner, A.P.F.; Rickman, A.G.; Harpin, A.P.R.; Shaw, M.P.; McKenzie, J.S.;  
Optical Techniques for Environmental Monitoring, IEE Colloquium on  
15 Nov 1995 Page(s):3/1 - 3/6  
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